

SCANNING ELECTRON MICROSCOPE (SEM)

MANUFACTURER : JEOL

MODEL : JSM 6400F

Analysis

- Resolution: 1.5 nm at 30 kV and at 8mm WD
- Magnification: 10X to 500 000X
- Probe current:: 10-12 to 10-10 A
- Electron gun: Cold-cathode field emission
- Detectors: Scintillator/photomultiplier
- GW Electronic System 47 backscattered detector
- Accelerating Voltage: 500V to 30kV
- Specimen Stage: Type: Fully Eucentric goniometer stage
 Movements: X = 100mm
 Y = 110mm
 Z = 34mm
 Tilt: -5° to 60°
 Rotation: 360° endless
- Specimen exchange: By airlock: Up to 150mm dia. Specimen holders
By stage drawout: 200mm dia. or larger specimen holders

Applications

- Surface characterization and elemental chemical analysis

Characteristics

- EDS Detector: Si(Li) (30mm²) Prism 2000 with Imix acquisition system allowing Be detection
- EBSD detector: Oxford HKL allowing crystallographic orientation

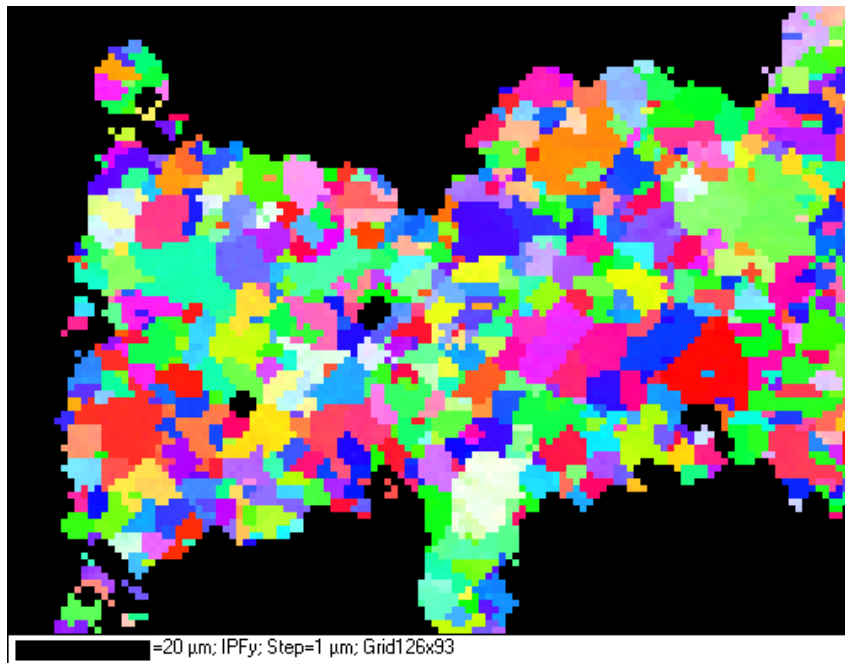
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Example

EBSD analysis on a copper VIA into an organic laminated



IPF colouring
Y1

Copper

